## **EXAMPLE A Performance Aware Dual Dielectric Assignment for Tunneling Current Reduction**

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### **Outline of the Talk**

Introduction ■ Why Dual-K and Dual-T Related Work DKDT Assignment Algorithm Cell Characterization for DKDT Conclusions



### Why Low-Power ?

#### Motivation: Extending battery life .....



Source: Power Integrations Inc



#### **Battery Lifetime**



#### **Environmental Concerns**



#### **Cooling and Energy Costs**



#### System Reliability



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Source: Weste and Harris 2005

# Leakages in Nanometer CMOS

- I<sub>1</sub>: reverse bias pn junction (both ON & OFF)
- I<sub>2</sub>: subthreshold leakage (OFF)
- I<sub>3</sub>: oxide tunneling current (both ON & OFF)
- $I_4$ : gate current due to hot carrier injection (both ON & OFF)
- $I_5$ : gate induced drain leakage (OFF)
- I<sub>6</sub>: channel punch through current (OFF)



# Engenneling paths in an Inverter

**Low Input :** Input supply feeds the tunneling current.

High Input : Gate supply feeds the tunneling current.







Source: Hansen 2004



Gate oxide tunneling current I<sub>gate</sub> [Kim2003, Chandrakasan2001] (k is a experimentally derived factors):

 $I_{gate} \, \alpha \, (V_{dd} \, / T_{gate})^2 \exp \left(-\,k \, T_{gate} / V_{dd}\right)$ 

Options for reduction of tunneling current :
 Decreasing of supply voltage V<sub>dd</sub> (will play its role)
 Increasing gate SiO<sub>2</sub> thickness T<sub>gate</sub> (opposed to the technology trend !!)



We believe that use of multiple dielectrics (denoted as  $K_{gate}$ ) of multiple thickness (denoted as  $T_{gate}$ ) will reduce the gate tunneling current significantly while maintaining the performance.

## Why Dual-K and Dual-T? (Low K<sub>gate</sub> Vs High K<sub>gate</sub>)



## Why Dual-K and Dual-T? (Low T<sub>gate</sub> Vs High T<sub>gate</sub>)



## Why Dual-K and Dual-T? **Four Combinations of K**gate & T<sub>gate</sub>)



(1)  $K_1 T_1$ 



(3)  $K_2 T_1$ 



(2) 
$$K_1 T_2$$



(4)  $K_2T_2$ 

Tunneling Current↓ Delay ↑

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# **Dielectrics for Replacement of SiO**<sub>2</sub>

- Silicon Oxynitride (SiO<sub>x</sub>N<sub>y</sub>) (K=5.7 for SiON)
- Silicon Nitride  $(Si_3N_4)$  (K=7)
- Oxides of :
  - Aluminum (Al), Titanium (Ti), Zirconium (Zr), Hafnium (Hf), Lanthanum (La), Yttrium (Y), Praseodymium (Pr),

• their mixed oxides with  $SiO_2$  and  $Al_2O_3$ 

■ **NOTE**: I<sub>gate</sub> is still dependent on T<sub>gate</sub> irrespective of dielectric material.

### Related Works Current Reduction)

Inukai et. al. in CICC2000: Boosted Gate MOS (BGMOS) device using dual T<sub>ox</sub> and dual V<sub>Th</sub> for both gate and subthreshold standby leakage reduction.

Rao et. al. in ESSCIRC2003: Sleep state assignment for MTCMOS circuits for reduction of both gate and subthreshold leakage.

### Related Works Commeling Current Reduction)

Lee et. al. in DAC2003 and TVLSI2004Feb : Pin reordering to minimize gate leakage during standby positions of NOR and NAND gates.

Sultania, et. al. in DAC2004 and ICCD2004: Heuristic for dual T<sub>ox</sub> assignment for tunneling current and delay tradeoff.



### **Related Works**

- Developed methods that use oxide of different thicknesses for tunneling reduction.
  Do not handle emerging dielectrics that will replace SiO<sub>2</sub> to reduce the tunneling current.
  Either consider ON or OFF state, but do not account both.
- Degradation in performance due to dual thickness approach.



## **Contributions of this Work**

- Introduces a new approach called dual dielectric assignment for tunneling current reduction.
- Considers dual thickness approach for both of the dielectrics.
- Explores a combined approach called DKDT (Dual-K of Dual Thickness) and proposes an assignment algorithm.
- Accounts the tunneling current for both ON and OFF state.
- Presents a methodology for logic gates characterization for worst-case tunneling considering non-SiO<sub>2</sub> dielectrics for low end nano-technology.





**Observation:** Tunneling current of logic gates increases and propagation delay decreases in the order  $K_2T_2$ ,  $K_2T_1$ ,  $K_1T_2$ , and  $K_1T_1$  (where,  $K_1 < K_2$  and  $T_1 < T_2$ ).

Strategy: Assign a higher order K and T to a logic gate under consideration
 To reduce tunneling current
 Provided increase in path-delay does not violate the target delay

# **Example 1 Assignment : Algorithm**

**Step 1:** Represent the network as a directed acyclic graph G(V, E).

Step 2: Initialize each vertex  $v \in G(V, E)$  with the values of tunneling current and delay for  $K_1T_1$  assignment.

Step 3: Find the set of all paths P{Π<sub>in</sub>} for all vertex in the set of primary inputs (Π<sub>in</sub>), leading to the primary outputs Π<sub>out</sub>.

Step 4: Compute the delay  $D_P$  for each path  $p \in P{\Pi_{in}}$ .



**Step 5:** Find the critical path delay  $D_{CP}$  for  $K_1T_1$  assignment.

**Step 6:** Mark the critical path(s)  $P_{CP}$ , where  $P_{CP}$  is subset  $P{\Pi_{in}}$ .

**Step 7:** Assign target delay  $D_T = D_{CP}$ .

Step 8: Traverse each node in the network and attempt to assign K-T in the order  $K_2T_2$ ,  $K_2T_1$ ,  $K_1T_2$ , and  $K_1T_1$  to reduce tunneling while maintaining performance.

# **DEADT** Assignment : Algorithm

(1) FOR each vertex  $v \in G(V, E)$ 

- (1) Determine all paths  $P_v$  to which node v belongs;
- (2) Assign  $K_2T_2$  to v;
- (3) Calculate new critical delay  $D_{CP}$ ;
- (4) Calculate slack in delay as  $\Delta D = D_T D_{CP}$ ;
- (5) IF ( $\Delta D < 0$ ) then
- (6) {

(2)

- (1) Assign  $K_2T_1$  to v; Calculate  $D_{CP}$ ; Calculate  $\Delta D$ ;
- (2) IF ( $\Delta D < 0$ ) then
- (3) {
- (1) Assign  $K_1T_2$  to v; Calculate  $D_{CP}$ ; Calculate  $\Delta D$ ; (2) IF ( $\Delta D < 0$ ) then

(1) reassign  $K_1T_1$  to v;

(4) } // end IF

(7) } // end IF (3) // end FOR 3/28/2005

### **KDT Assignment Algorithm** (Time Complexity)

- Assume that there are n number of gates in the original network representing any circuit.
- The statements from Step-01 to Step-03 take Θ(n<sup>2</sup>) time in worst case.
- The run time for statements from Step-04 to Step-07 are of  $\Theta(n^2)$  complexity.
- The heuristic loop which assigns DKDT takes Θ(n<sup>3</sup>) time.
- Thus, the overall worst case time complexity of the DKDT assignment algorithm is Θ(n<sup>3</sup>).



## **DKDT Algorithm : Demo**







#### NAND Network



## **DKDT Algorithm : Demo**



#### **Network with Node Delays**





Network with Path Delays (Fix,  $D_T = 2.64$ )

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#### Node1 : $K_2T_2$ ?





#### Node2 : $K_2T_2$ ?



#### $D_{CP} > D_T \rightarrow No \text{ for } K_2 T_2$



#### $D_{CP} > D_T \rightarrow No \text{ for } K_2 T_1$



#### $D_{CP} > D_T \rightarrow No \text{ for } K_1 T_2$



#### Node2 : Reassign $K_1T_1$







#### **Final Assignment**



- The Berkeley Predictive Technology Model (BPTM) has been used.
- The first step in the characterization was the selection of an appropriate capacitive load ( $C_{Load} = 10 * C_{ggPMOS}$  used).
- The supply voltage is held at  $V_{DD} = 0.7V$ .
- We define the delay as the time difference between the 50% level of input and output.

# **Big Cell Characterization : t**r

- For worst-case scenarios in the development of the algorithm, we chose the maximum delay time [i. e. maximum (t<sub>pdr</sub>, t<sub>pdf</sub>)].
- The effect of switching pulse rise time t<sub>r</sub> was initially examined on the delay characteristics.
- To eliminate an explicit dependence of the algorithm results on t<sub>r</sub>, we chose a value that is realistic yet does not affect the delay significantly.



#### **Delay Versus Rise Time**



# gic Cell Characterization : Igate

I gs I gcd I gcd I gb

#### **BSIM4** Model

Direct tunneling current is calculated by evaluating both the source and drain components.  $\Box$  For the logic gate,  $I_{gate} =$  $\Sigma_{\forall MOS} (|I_{gs}| + |I_{gd}|).$ This accounts for tunneling current contributions from devices in both the ON and OFF state.



The effect of varying dielectric material was modeled by calculating an equivalent oxide thickness  $(T^*_{ox})$  according to the formula:  $T^*_{ox} = (K_{gate} / K_{ox}) T_{gate}$ - Here, K<sub>gate</sub> is the dielectric constant of the gate dielectric material other than SiO<sub>2</sub>, (of thickness  $T_{\text{pate}}$ , while  $K_{\text{ox}}$  is the dielectric constant of SiO<sub>2</sub>.

# **Characterization : T**gate Modeling

The effect of varying oxide thickness T<sub>ox</sub> was incorporated by varying TOXE in SPICE model.
 Length of the device is proportionately changed to minimize the impact of higher dielectric thickness on the device performance :

 $L^* = (T^*_{ox} / T_{ox}) L$ 

Length and width of the transistors are chosen to maintain (W:L) ratio of (4:1) for NMOS and (8:1) for PMOS.



#### **Tunneling Current Vs Dielectric Constant**





#### **Tunneling Current Vs Dielectric Thickness**





# Characterization : T<sub>pd</sub> Vs K<sub>gate</sub>

#### **Propagation Delay Vs Dielectric Constant**





# Characterization : T<sub>pd</sub> Vs T<sub>gate</sub>

#### **Propagation Delay Vs Dielectric Thickness**



# Experimental Results: Setup

- DKDT algorithm was implemented in C and used along with SIS, and tested on the ISCAS'85 benchmarks.
- The library of gates consisting of four types of NAND and four types of inverters was characterized for the 45 nm technology using SPECTRE tool.
- We used K<sub>1</sub> = 3.9 (for SiO<sub>2</sub>), K<sub>2</sub> = 5.7 (for SiON), T<sub>1</sub> = 1.4 nm, and T<sub>2</sub> = 1.7 nm to perform our experiments.
  The value of T<sub>1</sub> is chosen as the default value from the BSIM4.4.0 model card and value of T<sub>2</sub> is intuitively chosen based on the characterization process.

### Experimental Results : Table

CKTs	Gates	Critical Delay (ps)	Current for K <sub>1</sub> T <sub>1</sub> (nA)	Current for DKDT (nA)	%Redu ction
<b>C17</b>	24	2.22	187.2	93.66	49.96
C432	160	6.67	4071.6	281.4	93.08
<b>C499</b>	202	3.56	5885.1	656.06	88.85
<b>C880</b>	383	10.68	6739.2	375.38	94.42
C1355	546	3.56	5885.1	305.16	94.81
<b>C1908</b>	880	11.57	10015.2	319.69	96.80
<b>C2670</b>	1193	42.71	18415.8	1734.08	90.85
<b>C3540</b>	1669	31.59	35708.4	2461.93	93.10
C5315	2406	40.04	29027.7	1220.89	95.79
<b>C6288</b>	2406	43.15	29355.3	413.96	98.59
<b>C7552</b>	3512	45.82	34947.9	695.38	98.01



## **DKDT** Algorithm Results

#### **Tunneling Current** and % Reduction



**Benchmark Circuits** 



### Comparative View : Table

Bench-	Sultania (	(100 nm)	Lee (100 nm)		DKDT (45 nm)	
mark	%Reduc	%Pena	%Redu	%Pena	%Redu	%Pena
Circuits	tion	lty	ction	lty	ction	lty
C432	83.8	24.6	59.52	NA	93.08	0
<b>C499</b>	70.2	25.4	28.25	NA	88.85	0
<b>C880</b>	92.3	25.5	45.43	NA	94.42	0
C1355	67.9	25.0	33.50	NA	94.81	0
<b>C1908</b>	82.3	25.2	27.76	NA	96.80	0
C2670	92.6	25.3	33.80	NA	90.58	0
C3540	91.4	25.1	36.40	NA	93.10	0
C5315	91.7	26.1	34.34	NA	95.79	0
C6288	62.7	25.7	45.86	NA	98.59	0
C7552	91.6	25.3	28.10	NA	98.01	0





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- New approach DKDT for tunneling current reduction accounting for both the ON and OFF states.
- Polynomial time complexity heuristic algorithm could carry out such DKDT assignment for benchmark circuits in reasonable amount of time.
  Experiments prove significant reductions in tunneling current without performance penalty.



- Modeling of other high-K dielectrics is under progress.
- Development of optimal assignment algorithm can be considered.
- Tradeoff of tunneling, area and performance needs to be explored.
- DKDT based design may need more masks for the lithographic process during fabrication.

### The Latest Chip Designed Ceaim: Lowest power consuming image watermarking chip available at present)





Technology : TSMC 0.25 µ Total Area : 16.2 sq mm Dual Clocks : 280 MHz and 70 MHz Dual Voltages : 2.5V and 1.5V No. of Transistors : 1.4 million Avg. Power Consumption : 0.3 mW



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